US Application No. 10/571,267 Attorney Docket No.: Q93721 PRELIMINARY AMENDMENT

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## **AMENDMENTS TO THE SPECIFICATION**

On page 1, beginning with "Description" and ending with "...such lithography objective", please replace the present title with the following amended title:

LITHOGRAPHY LENS SYSTEM AND PROJECTION EXPOSURE SYSTEM PROVIDED

WITH AT LEAST ONE LITHOGRAPHY LENS SYSTEM OF THIS TYPE

Amend the specification by adding before the first line the sentence:

This application is a National Stage of International Application No.

PCT/EP2004/007753, filed July 14, 2004, which claims benefit of German Application No. 103
41 986.1, filed September 9, 2003.